IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

SEP 0 8 2006 blicant:

Craig K. Carlson-Stevemer

Examiner: Jermele M. Hollington

erial No.:

10/622,849

Group Art Unit: 2829

Filed:

July 18, 2003

Docket No.: A126.114.102

Due Date:

September 3, 2006

Title:

WAFER STAGING PLATFORM FOR A WAFER INSPECTION SYSTEM

AMENDMENT AND RESPONSE

Mail Stop Amendment **Commissioner for Patents** P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir/Madam:

This Amendment and Response is in reply to the Non-Final Office Action mailed May 3, 2006. Please amend the above-identified patent application as follows: